

# Artificial afferent neurons based on the metal-insulator transition of VO<sub>2</sub>

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**Abstract** Neuromorphic computing offers significant advantages in addressing data redundancy and enhancing system energy efficiency. Although extensive research has been conducted on pulsed neural networks and bionic sensors, the development of artificial electronic afferent neurons for low-energy information transfer remains limited. This study introduces an artificial afferent neuron comprising a vanadium dioxide (VO<sub>2</sub>) device, capacitor and resistor. The VO<sub>2</sub> devices exhibit stable electrically induced metal-insulator transition (MIT). Leveraging the MIT of this device, we develop an artificial afferent neuron to transform constant or sinusoidal analog signals into pulsed voltage signals. The output frequency increases with the increase of the input voltage, mimicking the faster pulse outputs of biological afferent neurons in response to stronger stimuli.

**Keywords** vanadium dioxide, metal-insulator transition, artificial afferent neurons, pulsed voltage signal, output frequency

## 1 Introduction

Owing to advancements in neuromorphic computing and bionic sensing [1], bionic intelligent robots have gained considerable attention. Bionic intelligent robots are predominantly designed to emulate biological perceptual systems, featuring effective information processing and rapid responses. Biological perceptual systems are complex, efficient, fault-tolerant, consisting of sensory receptors, afferent neurons, and a cerebral cortex [2–4]. In recent years, pulsed neural networks have been extensively investigated to simulate the cerebral cortex [5–10]. Owing to their synaptic plasticity, resistive random access memories (RRAMs) [11], phase-change memories (PCMs) [12], ferroelectric field-effect transistors (FeFETs) [13,14] and semiconductor-nanocrystal transistors [15–18] are considered potentially key components in artificial pulsed neural networks. External stimuli such as light, sound, smell, and pressure are typically conveyed as continuous analog signals, differing from the pulsed signals required by the central nervous system. Therefore, artificial afferent neurons designed to convert continuous analog signals into pulsed signals are required to facilitate information transfer between bionic sensors and the pulsed neural network [19–21].

Kim et al. [22] designed a tactile sensing system that integrated pressure sensors, organic ring oscillators, and neuromorphic transistors on a flexible substrate. The circular oscillator functioned similarly to biological afferent neurons, converting the voltage signal received from a pressure sensor into voltage pulses to drive synaptic devices and generate postsynaptic currents. However, the extensive use of metal-oxide-semiconductor field-effect transistor (MOSFET) circular oscillators in tactile sensing systems complicates circuit structures, limiting the application of electronic afferent neurons in high-density neuromorphic intelligence chips. Tan et al. [23] combined a ring oscillator, an edge detector, and a light-emitting diode

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(LED) to develop an optoelectronic afferent neuron capable of emitting light pulses. The optoelectronic afferent neuron was then connected to an MXene-based pressure sensor and a neural synaptic device based on an ITO/ZnO/NSTO photomemristor, leading to the development of a tactile sensing system based on optoelectronic devices. Yu et al. [24] proposed an artificial afferent neuron activated through contact electrification at femtojoule energy levels. External mechanical actions were easily converted into voltage spikes using a triboelectric nanogenerator (TENG). The triboelectric potential generated by charge transfer during contact electrification activated postsynaptic transistors, enabling spatiotemporal recognition of displacements, pressures, and touch patterns. Moreover, the converted mechanical energy could be harnessed to achieve the self-powered operation of artificial sensory neurons, resulting in a significant reduction in energy consumption. However, these structures are exclusively applicable to piezoelectric sensors, which are not readily extended to resistive sensors. Zhang et al. [21] developed an electron-afferent neuron leveraging the properties of the electrogenic metal-insulator transition (MIT) of  $\text{NbO}_x$  to generate pulse output, thereby simplifying the circuit structure. However, the rather high MIT temperature of  $\text{NbO}_x$  (1080 K) poses a challenge for the future development of low-power-driven neural devices.

In this study, we fabricate a  $\text{VO}_2$  film with stable MIT. The switching performance of  $\text{VO}_2$  surpasses that of  $\text{NbO}_2$ , demonstrating a faster switching speed and lower energy consumption. Notably, the simulated Mott transition occurs 100 times faster in  $\text{VO}_2$  than in  $\text{NbO}_2$ . The corresponding energy consumption in  $\text{VO}_2$  is approximately 16% of that in  $\text{NbO}_2$  [25]. Consequently, these findings show promise for the development of future low-power-driven neural devices. The  $\text{VO}_2$  film is employed to fabricate  $\text{VO}_2$  devices with horizontal structures. These  $\text{VO}_2$  devices exhibit electrically induced MIT under a low driving voltage, bidirectional Mott transitions, high uniformity and good endurance. An artificial afferent neuron with a simple circuit structure comprising a  $\text{VO}_2$  device, capacitor, and resistor is then fabricated. This configuration enables the transformation of continuous analog signals into pulsed voltage signals. Notably, the output frequency increases with the increase of input voltages. This behavior faithfully mimics the phenomenon observed in biological afferent neurons, where stronger stimuli leads to faster pulse outputs. Our  $\text{VO}_2$ -based artificial afferent neuron offers a promising option for the development of low-power and highly integrated artificial impulse neural networks.

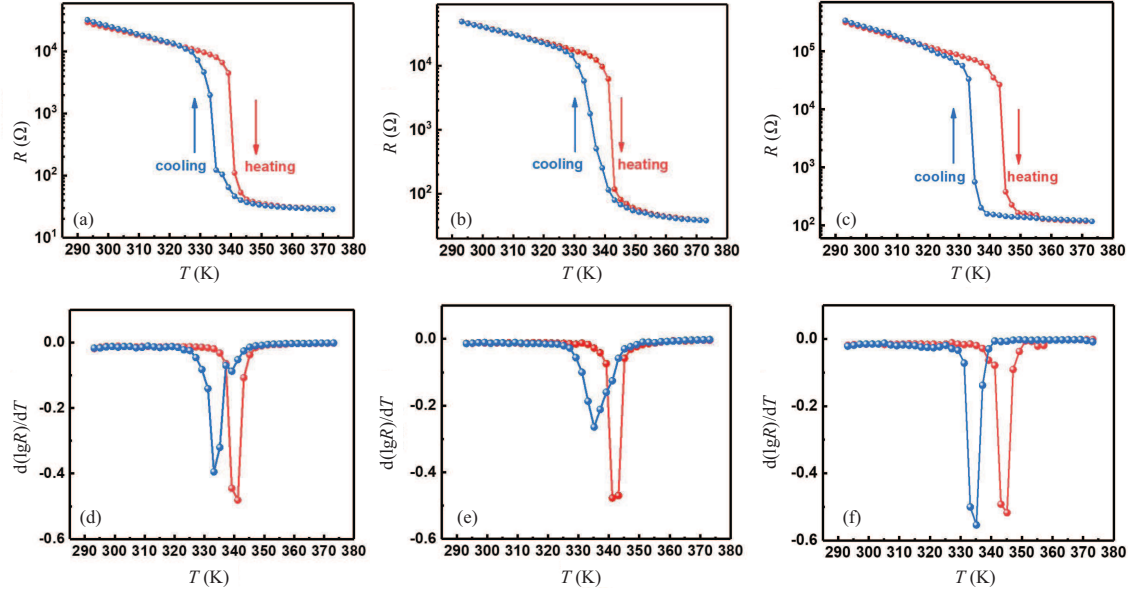
## 2 Experimental section

The top Si layer of the SOI wafer was first removed via ICP etching to obtain a  $\text{SiO}_2/\text{Si}$  substrate. Photolithography was employed to determine the pattern of the  $\text{VO}_x$  film on the  $\text{SiO}_2/\text{Si}$  substrate. The  $\text{VO}_x$  films were deposited at a fixed oxygen partial pressure of 5% using magnetron sputtering. The photoresist was subsequently removed via a lift-off process to obtain  $\text{VO}_x$  strips with dimensions of  $20\ \mu\text{m} \times 45\ \mu\text{m}$ . The  $\text{VO}_x$  strips on the  $\text{SiO}_2/\text{Si}$  substrate underwent annealing at  $500^\circ\text{C}$  for 120 min to promote the crystallization of  $\text{VO}_x$  into  $\text{VO}_2$ . Photolithography was repeated to define the patterns of the electrodes on the  $\text{VO}_2$  strips. Electrodes consisting of 5 nm Ni and 250 nm Au were prepared using magnetron sputtering. Finally, the photoresist was removed using a lift-off process, resulting in  $\text{VO}_2$  devices with a horizontal structure. Scanning electron microscopy (SEM, Gemini500), atomic force microscopy (AFM, Multimode-8), and Raman spectroscopy (Senterra) with a 532 nm laser were employed to examine the microstructures of the  $\text{VO}_2$  films and devices. Electrical characterization was performed using a semiconductor parameter analyzer (FS480, PDA Co. Ltd.).

## 3 Results and discussion

### 3.1 MIT of $\text{VO}_2$

Figures 1(a)–(c) show the temperature-dependent resistances of the  $\text{VO}_2$  films with different deposition times. The thicknesses of the  $\text{VO}_2$  films under the deposition times of 300, 600, and 1200 s are approximately 113, 166, and 255 nm, respectively. The resistance curves indicate a clear hysteresis phenomenon owing to the latent thermal properties of  $\text{VO}_2$ . All  $\text{VO}_2$  films exhibit temperature-dependent resistance changes greater than three orders of magnitude. The transition temperature of the MIT ( $T_{\text{MIT}}$ ) for the  $\text{VO}_2$  films is determined by calculating the first-order derivative of the logarithm of the resistance given by the heating and cooling curves with respect to the temperature, as shown in Figures 1(d)–(f). The



**Figure 1** (Color online) Resistance-temperature ( $R$ - $T$ ) plots for  $\text{VO}_2$  films with deposition times of (a) 300 s, (b) 600 s, and (c) 1200 s. Corresponding  $(\frac{d(\lg R)}{dT})$ - $T$  plots for  $\text{VO}_2$  films with deposition times of (d) 300 s, (e) 600 s, and (f) 1200 s.

**Table 1**  $T_{\text{MIT}}$  of  $\text{VO}_2$  films with varying thicknesses during heating and cooling

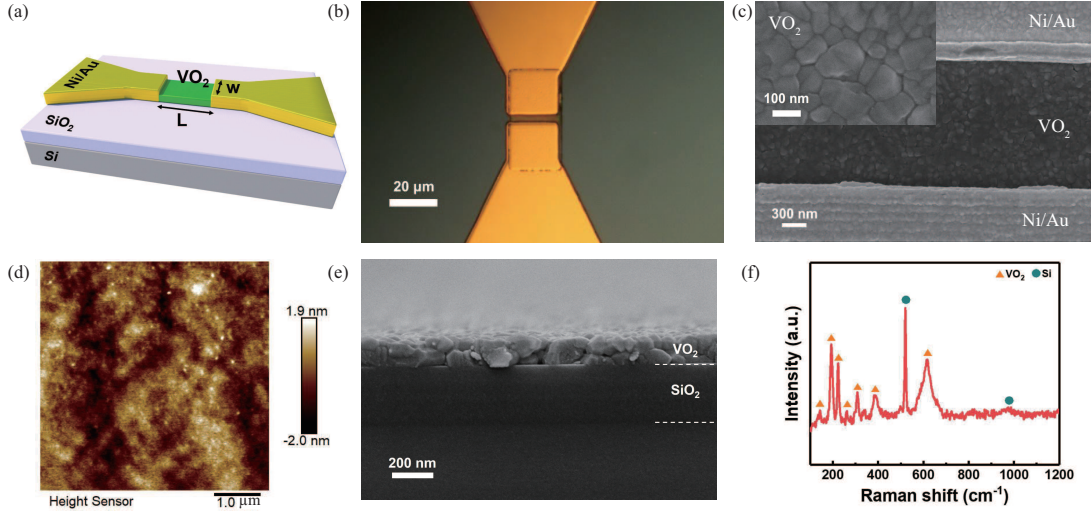
| Deposition time of $\text{VO}_2$ (s) | Thickness of $\text{VO}_2$ (nm) | $T_{\text{MIT}}$ (heating) (K) | $T_{\text{MIT}}$ (cooling) (K) |
|--------------------------------------|---------------------------------|--------------------------------|--------------------------------|
| 300                                  | 113                             | 341                            | 333                            |
| 600                                  | 166                             | 341                            | 335                            |
| 1200                                 | 255                             | 345                            | 335                            |

$T_{\text{MIT}}$  values of the  $\text{VO}_2$  films with varying thicknesses during heating and cooling are listed in Table 1. The  $T_{\text{MIT}}$  of the  $\text{VO}_2$  films is close to that of bulk  $\text{VO}_2$  (341 K), indicating the high uniformity and excellent performance of the deposited  $\text{VO}_2$  films [26].

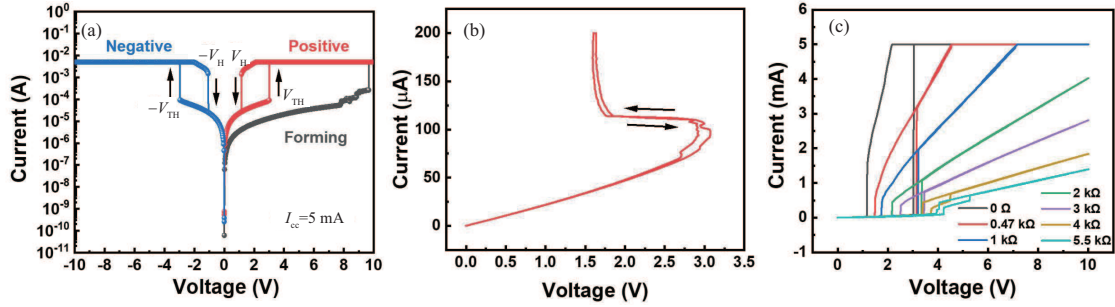
### 3.2 Preparation and characterization of $\text{VO}_2$ devices with horizontal structure

The horizontal structure of the  $\text{VO}_2$  device is shown in Figure 2(a). Figure 2(b) shows an optical image of a typical  $\text{VO}_2$  device, showcasing the precise alignment of the electrodes with the  $\text{VO}_2$  film. The channel between the electrodes measures 2.5  $\mu\text{m}$  in length and 20  $\mu\text{m}$  in width. The surfaces of the electrodes are smooth and flat without any photoresist residue. The SEM image in Figure 2(c) reveals the uniform grain size of the  $\text{VO}_2$  film with a deposition time of 300 s. Furthermore, the inset in Figure 2(c) shows a high-resolution SEM image of the  $\text{VO}_2$  film, indicating the absence of macroscopic defects, such as agglomeration or pinholes. The smooth surface of the  $\text{VO}_2$  film (roughness of  $\sim 0.5$  nm) is confirmed by AFM (Figure 2(d)). The cross-sectional SEM image in Figure 2(e) reveals a smooth and abrupt interface between the  $\text{VO}_2$  film and the Si/SiO<sub>2</sub> substrate. Figure 2(f) shows the characteristic peaks in the Raman spectrum of the device, where clear  $\text{VO}_2$ -related peaks indicate the high crystallinity of the  $\text{VO}_2$  film.

To characterize the electrically induced MIT of the  $\text{VO}_2$  device, the  $I$ - $V$  characteristic of the device is tested in DC mode, scanning from  $-10$  to  $10$  V, as shown in Figure 3(a). Following the forming process, the  $\text{VO}_2$  device exhibits stable electrically induced MIT behavior under both positive and negative voltages, and the absolute values of the transition voltages are approximately equal. The absolute value of the threshold voltage ( $V_{\text{TH}}$ ) is  $\sim 3.0$  V, whereas the absolute value of the hold voltage ( $V_H$ ) is  $\sim 1.4$  V. The resistance value of the device in the metallic state (LRS) is approximately 530  $\Omega$  at a voltage of 1.6 V. Figure 3(b) shows the  $I$ - $V$  plot of the current sweep after forming. Initially, as the current increases from 0 to 110  $\mu\text{A}$ , the voltage of the device increases linearly. The voltage subsequently exhibits a super-linear increase, indicating an increase in the temperature of  $\text{VO}_2$ . When the voltage reaches 3.0 V, the device undergoes an MIT. The  $\text{VO}_2$  film instantaneously changes from the insulating state to the metallic state. Metallic  $\text{VO}_2$  subsequently experiences a decrease in resistance as the current increases owing to Joule heating, resulting in a reduction in the voltage. When the current decreases from 200 to



**Figure 2** (Color online) (a) Schematic and (b) optical image of the VO<sub>2</sub> devices with a horizontal structure. (c) SEM and (d) AFM images of the VO<sub>2</sub> surface. (e) Cross-sectional SEM image and (f) Raman spectrum of the VO<sub>2</sub> film.



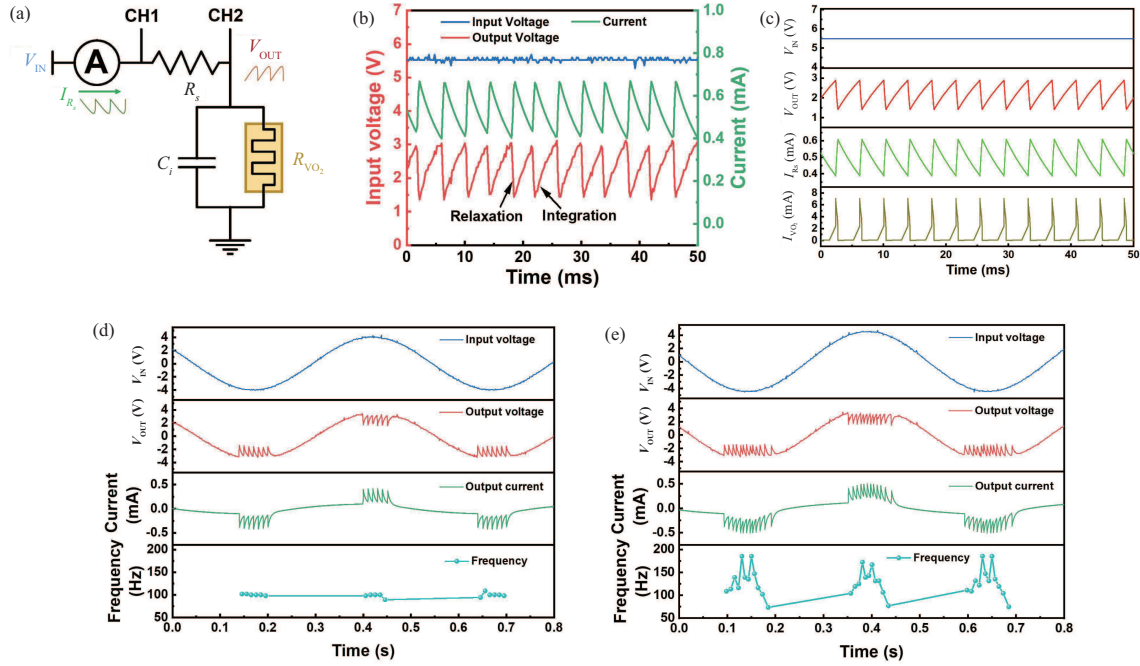
**Figure 3** (Color online) (a) Forward and reverse DC operation of the VO<sub>2</sub> device under a voltage sweep; (b) DC operation of the VO<sub>2</sub> device under a current sweep; (c) DC operation of the VO<sub>2</sub> device in series with resistors of different values.

0  $\mu\text{A}$ , the resistance of the device increases as the current decreases. When the voltage reaches 1.7 V, the VO<sub>2</sub> film undergoes an MIT from the metallic state to the insulating state. This transition causes a sudden increase in the resistance, leading to an abrupt increase in the voltage across the VO<sub>2</sub> film. The critical current for the MIT transition of the device is approximately 110  $\mu\text{A}$  with a window of 3  $\mu\text{A}$ . This narrow window suggests that the transition temperatures between the insulating and metallic states of the VO<sub>2</sub> device are similar [27]. Figure 3(c) shows the  $I$ - $V$  plot when the VO<sub>2</sub> device is connected in series with different resistors. As the resistance of the series resistor increases, both  $V_{\text{TH}}$  and  $V_{\text{H}}$  increase. This phenomenon can be attributed to the voltage applied across the resistor and VO<sub>2</sub> device. As the resistance of the resistor increases, the voltage applied across the VO<sub>2</sub> device decreases, necessitating a higher total voltage to achieve the desired  $V_{\text{TH}}$  across the VO<sub>2</sub> device.

### 3.3 Fabrication and characterization of artificial afferent neurons

In biological sensory systems, afferent neurons are primarily responsible for converting analog signals received from sensory receptors, such as external images, sounds, and temperatures, into pulse signals required for brain processing [28,29]. In this study, an electronic afferent neuron is fabricated by combining a VO<sub>2</sub> device with a capacitor and resistor. This circuit is illustrated in Figure 4(a). The electronic afferent neuron is formed by connecting the VO<sub>2</sub> device in parallel with a capacitor of capacitance  $C_i$ , and then in series with a resistor of resistance  $R_S$ . When the voltage ( $V_{\text{IN}}$ ) of the input signal exceeds a certain value, the ungrounded end of the VO<sub>2</sub> device outputs a pulse signal with a certain frequency ( $V_{\text{OUT}}$ ).

The capacitance of the entire circuit is given by  $C = C_i + C_{\text{par}}$ , where  $C_{\text{par}}$  is the parasitic capacitance, and  $R_{\text{met}} \ll R_S \ll R_{\text{ins}}$ , where  $R_{\text{ins}}$  and  $R_{\text{met}}$  represent the insulating and metallic state resistances of the VO<sub>2</sub> device, respectively. Because  $R_{\text{ins}}C \gg R_S C$ , when  $V_{\text{IN}}$  is applied to the input terminal, the



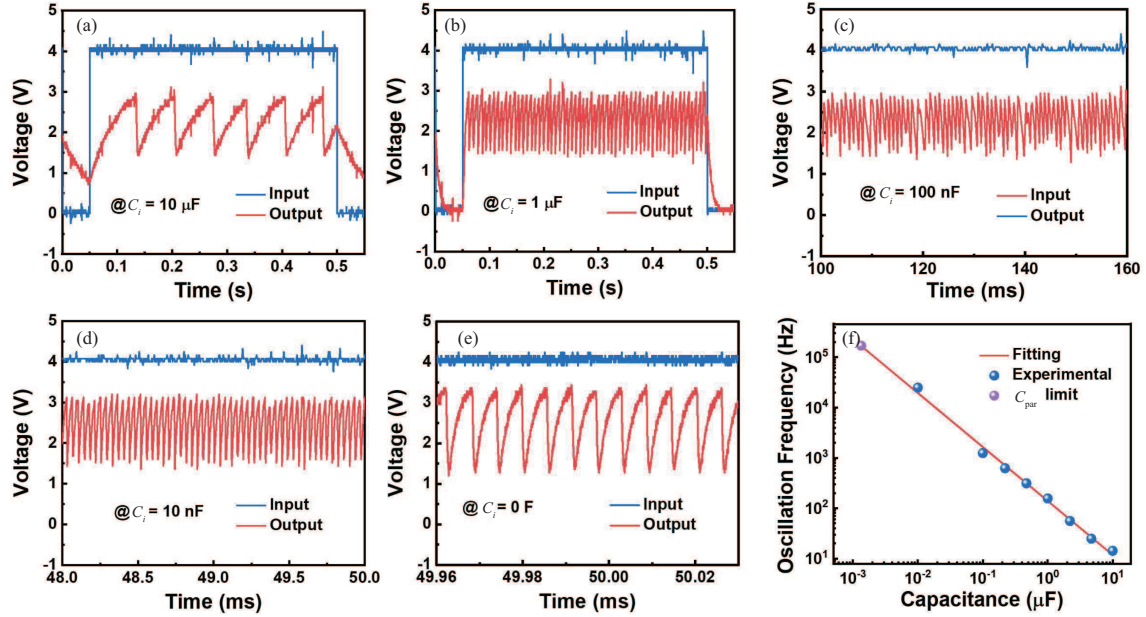
**Figure 4** (Color online) (a) Circuit diagram of the artificial afferent neuron. (b) Oscillatory behavior of the artificial afferent neuron. (c) Oscillatory behavior of the simulated afferent neuron. Frequency response for sinusoidal input signals with amplitudes of (d) 4.0 V and (e) 4.5 V.

capacitor undergoes a charging process. During the charging process, the voltage across the capacitor  $V_{OUT}$  increases continuously until it exceeds  $V_{TH}$ , at which point the  $VO_2$  film undergoes MIT owing to Joule heating. At this stage, the resistance decreases from  $R_{ins}$  to  $R_{met}$ . Since  $R_{met}C \ll R_s C$ , the MIT transition leads to the discharge of the capacitance  $C$ . Consequently, the net charge of the capacitor decreases.  $V_{OUT}$  also gradually decreases until it becomes lower than  $V_H$ . When the Joule heating of the  $VO_2$  device is insufficient to maintain the metallic state,  $VO_2$  transitions from the metallic state to the insulating state, causing the resistance of  $VO_2$  to return to  $R_{ins}$ . Subsequently, the MIT is accompanied by repeated charging and discharging of the capacitor, resulting in periodic  $V_{OUT}$ .

To achieve the oscillation output of the circuit, the electronic afferent neuron operates with  $R_s$  at 6.7 k $\Omega$ ,  $V_{IN}$  at 5.5 V, and  $C_i$  at 1  $\mu$ F, following the principles of  $VO_2$ -based relaxation oscillators [30]. As shown in Figure 4(b), the variation in  $V_{OUT}$  directly opposes the trend of the current variation, switching back and forth between  $V_H$  and  $V_{TH}$ . The charging time for  $V_{OUT}$  to change from  $V_H$  to  $V_{TH}$  is defined as the integration time, while the discharge time required for  $V_{OUT}$  to change from  $V_{TH}$  to  $V_H$  is defined as the relaxation time. However, the current  $I_{VO_2}$  through the  $VO_2$  device cannot be determined because of the inherent constraints of the test conditions. To obtain  $I_{VO_2}$ , the output characteristics of the oscillation circuit are simulated using LT-Spice [30]. The simulated results for  $V_{OUT}$ ,  $I_{VO_2}$ , and the current  $I_{R_s}$  flowing through  $R_s$  are shown in Figure 4(c). The simulated  $V_{OUT}$  and  $I_{R_s}$  values align well with the measured results shown in Figure 4(b). Moreover,  $I_{VO_2}$  exhibits oscillatory behavior, showing a linear increase during capacitor charging and a decline during capacitor discharging.

The  $VO_2$  afferent neurons are further investigated under a sinusoidal voltage signal  $V_{IN}$ . As shown in Figures 4(d) and (e), the second and third rows present the temporal variations of  $V_{OUT}$  and  $I_{R_s}$ , while the fourth row shows the frequency calculated from the output signal. When the input signal amplitude is 4.0 V (Figure 4(d)), the output frequencies of the afferent neurons are fixed at approximately 100 Hz. Furthermore, when the input signal is increased to 4.5 V (Figure 4(e)), the output frequencies also increase accordingly. This behavior faithfully mimics the phenomenon in which biological afferent neurons exhibit faster pulse outputs under stronger stimuli.

In addition to the MIT relaxation time, the oscillation frequency of the  $VO_2$  afferent neurons is primarily determined by the charging rate of the capacitor. Consequently, the limit of the oscillation frequency primarily depends on the parasitic capacitance of the circuit [31]. The parasitic capacitance of the test circuit is determined by reducing the external capacitance of the  $VO_2$  device until the oscillation fre-



**Figure 5** (Color online) Oscillation curves of the artificial afferent neurons at  $V_{IN} = 4 \text{ V}$  with different capacitances of external parallel capacitors: (a)  $C_i = 10 \mu\text{F}$ , (b)  $C_i = 1 \mu\text{F}$ , (c)  $C_i = 100 \text{ nF}$ , (d)  $C_i = 10 \text{ nF}$ , and (e)  $C_i = 0 \text{ F}$ . (f) Relationship between the oscillation frequency and the capacitance.

quency reaches its maximum value. Figures 5(a)–(e) show the oscillatory curves of the artificial afferent neurons versus the oscillation frequency of the circuit for different external capacitances. Figure 5(f) shows the linear relationship between the logarithm of the oscillation frequency and the logarithm of the capacitance, indicating that the oscillation frequency is inversely proportional to the capacitance. Figure 5(e) shows that the output oscillation frequency reaches its maximum value at 0.17 MHz when  $C_i = 0$ . By extrapolating the linearly fitted line in Figure 5(f), it is found that the parasitic capacitance of the entire circuit is 1.1 nF, which closely aligns with the reported value of parasitic capacitance in a circuit with a similar structure [30]. When constructing an electronic afferent neuron, appropriate capacitors should be selected to match the oscillation frequency of the afferent neuron with the maximum sampling frequency of the testing system.

## 4 Conclusion

In summary, we successfully prepared patterned  $\text{VO}_2$  thin films using lithography, sputtering, lift-off, and annealing processes and subsequently fabricated  $\text{VO}_2$  devices with a horizontal structure. The  $\text{VO}_2$  films exhibit a stable transition between the metallic and insulating states within a narrow temperature range of 333–345 K. The  $\text{VO}_2$  devices exhibit a stable electrically induced MIT under both positive and negative voltages. Moreover, the absolute values of the transition voltages are approximately equal. Finally, an artificial afferent neuron comprising a  $\text{VO}_2$  device, capacitor, and resistor is designed to transform constant or sinusoidal analog signals into pulsed voltage signals under suitable  $V_{IN}$  and  $R_S$ . Furthermore, the parasitic capacitance of the  $\text{VO}_2$  artificial afferent neuron is examined. We hope that the current  $\text{VO}_2$ -based artificial afferent neuron may significantly contribute to signal transformation in artificial neural networks.

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